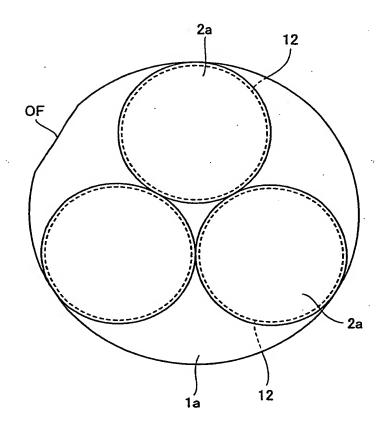
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Title: Method of Manufacturing Single-Crystal Semiconductor Wafers and Laser Machining Apparatus Therefor

FIG. 1



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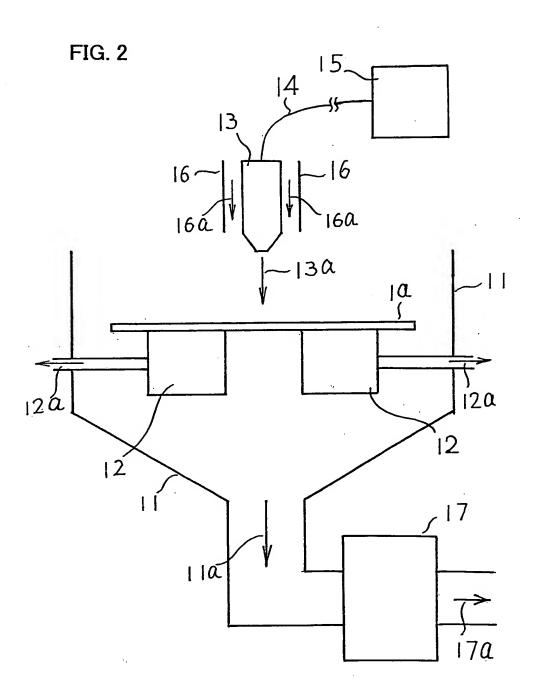
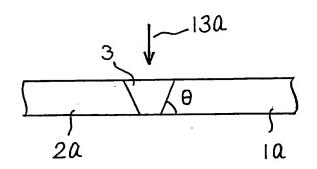


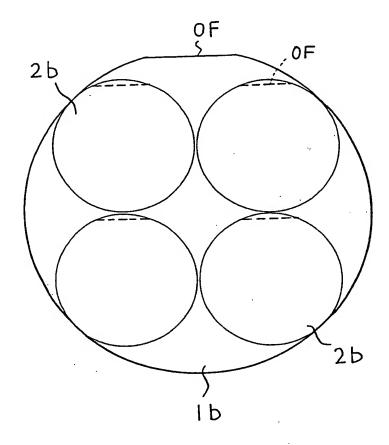
FIG. 3



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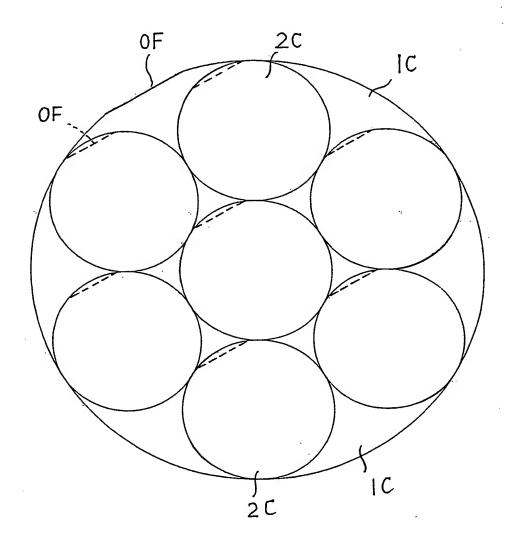
FIG. 4



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FIG. 5



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FIG. 6

